



Seat No. _____

H-003-0491101

B. Sc./M. Sc. (Applied Physics) (Sem. X) (CBCS) Examination

April - 2023

Ion Beams in Materials Science : Paper-13 (Core-10)

(New Course)

Faculty Code : 003

Subject Code : 0491101

Time : $2\frac{1}{2}$ / Total Marks : 70

Instructions :

- (1) All questions are compulsory.
- (2) Numbers in the right margin indicate marks.

1 Attempt any seven short questions : (two marks each) **14**

- (1) What do you mean by Ostwald ripening ?
- (2) Explain the term : RBS, ERDA and NRA.
- (3) What do you mean by SIMS ?
- (4) What is Fick's law of diffusion ?
- (5) Define : ion range and distribution and ion channeling.
- (6) What do you mean by effective charge of moving ion ?
- (7) What is the sputter yield ? Write any two applications of sputtering ?
- (8) Write down the advantages of ion implantation.
- (9) Define kinematic factor for RBS.
- (10) List the name of two synthesis methods for nanostructures based on ion beam.

2 Write the answer of any two questions : **14**

- (1) Write a detailed note on Linhard Scharff model.
- (2) Describe in detail : Firsov model.
- (3) Describe Fermi - Teller model for electronic stopping of low energy ions.
- (4) Define sputtering process. Write a short note on nuclear and electronic sputtering.

- 3** Write the answer of any two questions : **14**
- (1) What is the importance of ion implantation in the creation of controlled defects ? Explain point defects, line defects, and columnar defects produced by energetic ion irradiation.
 - (2) Write a short note on the radiation enhanced diffusion process. State the difference between Schottky defect and Frenkel defects.
 - (3) Give a brief overview of what energetic ions can do while interacting with the material.
 - (4) What do you mean by ion implantation ? Explain with its applications in material science.
- 4** Write the answer of any two questions : **14**
- (1) Explain about nano patterning of ripple formation.
 - (2) Discuss the formation of nanodots by ion beam technique.
 - (3) Explain the ion track formation in thin film with its limitations.
 - (4) What is ion beam mixing ? Discuss importance of the ion beam mixing for the synthesis of alloys.
- 5** Write the answer of any two questions : **14**
- (1) Discuss the advantages and limitations of ERDA.
 - (2) What do you mean by RBS technique ? Explain the uses, strengths and limitations of RBS technique.
 - (3) Describe working principle of the NRA. Why NRA is used to measure the low Z-elements ? Write down the parameters which determine the (a) energy and (b) yield of the emitted particle in case of NRA ?
 - (4) What do you mean by SIMS ? Explain its working.
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